Monitoring the Material Quality of Two-Dimensional Transition Metal Dichalcogenides

Jinhuan Wang, Chen Huang, Yilong You, Quanlin Guo, Guodong Xue, Hao Hong, Qingze Jiao, Dapeng Yu, Lena Du, Yun Zhao, and Kaihui Liu*

ABSTRACT: Two-dimensional (2D) transition metal dichalcogenides (TMDs), with atomic thickness, strong spin–orbit coupling, enhanced light-matter interactions, and facile quantum control ability, have demonstrated great potential in the applications of nanoelectronics and optoelectronics. The realization of these high-performance applications strongly relies on the production of large-scale TMD films with high quality. Therefore, facile and accurate quality monitoring of TMDs is essential for their future applications. In this Review, we summarized the main defect types in TMD crystals obtained by different synthesis methods, and we discussed recent cutting-edge characterization techniques, including scanning transmission electron microscopy, etching or adsorption, optical spectroscopy, and field-effect transistors. Finally, we provide a short perspective on the future development of quality monitoring techniques for broad 2D materials.

1. INTRODUCTION

Two-dimensional (2D) transition metal dichalcogenides (TMDs) are representative layered inorganic semiconductors with the formula MX$_2$, where M is a transition metal atom (e.g., Mo and W), and X is a chalcogen atom (S, Se, or Te). The M atom is covalently sandwiched between two X atoms forming a hexagonal honeycomb lattice structure in a single layer, and adjacent layers interact via weak van der Waals forces. In 1963, an ultrathin single-crystal MoS$_2$ was obtained for the first time by peeling from a large crystal of MoS$_2$. Subsequently, in 1986, monolayer MoS$_2$ was exfoliated by intercalation with lithium and reaction with water. However, it was not until monolayer graphene was obtained in 2004 that TMDs began to be intensively investigated. In contrast to the gapless semimetal graphene, TMDs possess direct energy band gaps in the near-infrared to visible spectral region at the two inequivalent K and K' momentum valleys in the Brillouin zone. Due to strong spin–orbit interactions, these two valleys couple to the electron spin and exhibit valley-selective light interactions. Such novel electronic structures make TMDs promising for an enormous range of advanced applications in lasers, memory devices, photo-detectors and extremely thin channel transistors. High-performance applications of TMDs are guaranteed by the production of high-quality material. In terms of sample preparation, 2D TMDs can be synthesized through top-down methods, including mechanical exfoliation and liquid phase exfoliation, and bottom-up methods mainly including molecular beam epitaxy (MBE) and chemical vapor deposition (CVD). However, due to the 2D nature and ultrahigh specific surface areas of TMDs, it is impossible to avoid introducing defects during sample synthesis with any method. These lattice defects can be divided into two main types: point defects in individual island and grain boundaries (GBs) between two stitched islands. Different from that of the single-element materials (such as graphene), the formation of point defects in TMDs is mainly due to the insufficient supply of the transition metal or the chalcogen precursor, as it is particularly difficult to precisely control these two compounds. GBs in polycrystalline TMDs result from the stitching of grains with random grain orientations during the growth. The presence of defects significantly influences the intrinsic properties of 2D TMDs. Those defects acting as scattering centers introduce strongly localized midgap states in the electronic structure, which may result in failing to open new transport channels and reduce the mobility of charge carriers.

Received: January 4, 2022
Revised: February 11, 2022
carriers through the intrinsic conduction or valence band.\textsuperscript{80} Defects will bring in more nonradiative recombination channels in TMDs, and thus reduce the exciton lifetime and PL quantum yield.\textsuperscript{81} While, those defects can also bring many exotic applications. For example, the trapped exciton by defects in TMDs can be an ideal sources of single photon emitters.\textsuperscript{82} Defects in TMDs can serve as new catalytic sites used to promote hydrogen evolution reactions.\textsuperscript{83}–\textsuperscript{86} Hence, building a standard set of defect characterization techniques for systematically monitoring the material quality of TMDs is a prerequisite for real application of these materials.

For the material quality monitoring of traditional semiconductor materials (e.g., silicon, germanium, and gallium arsenide), a series of national standards have been established. For example, the crystallization defects of silicon can be identified by the chemically preferential etching techniques, and the contents of substitutional carbon and interstitial oxygen can be monitored by infrared absorption spectroscopy. Furthermore, the monitoring of electrical performances such as the resistivity, conductivity type, and minority carrier lifetime have formulated standardized methods to meet quality requirements. Nevertheless, unlike traditional bulk semiconductor materials, where defects and impurities are embedded inside the crystal, the particularity of 2D materials limits the distribution of all defects on the surface of the material. This intrinsic feature provides a unique opportunity to detect defects in 2D materials by different means of surface sciences.

In this review, we considered the defects in TMDs in detail and summarized four key quality characterization (the characterization of defects) techniques (Figure 1): namely, atomic-scale characterization by scanning transmission electron microscopy (STEM); defect visualization by etching or adsorption; high-throughput characterization by optical spectroscopy such as Raman spectroscopy, second harmonic generation (SHG), and photoluminescence (PL); and electrical transport measurement by field-effect transistors (FETs). The accurate monitoring and comprehensive understanding of defects in TMDs are of great importance for the improvement of TMD quality and the realization of superior behaviors in their potential applications.

2. QUALITY CHARACTERIZATION TECHNIQUES FOR TMDs

2.1. Atomic-Scale Characterization by STEM. As an indispensable component of materials science, microscopy and microanalysis are important methods to practice “seeing is believing” and to explore the microscopic world. In recent years, the development of spherical aberration correction technology has further improved the spatial resolution of transmission electron microscopy (TEM), enabling the imaging of individual atoms. Benefiting from this, high-resolution TEM (HRTEM) and STEM are common techniques for characterizing the atomic structure of 2D TMDs. With these techniques, the structures of defects in TMDs can be clearly observed.\textsuperscript{37,88} Different from the isotropy of 3D crystal structure, 2D TMDs possess layered structure with atomically thin thickness. As STEM delivers the projection of the sample along with the beam direction, ultimate thickness of TMDs facilitate the identify of atomic position. In contrast, the atomically precise characterization of 3D atomic structures remains difficult.

HRTEM is an imaging technique based on phase contrast that enables direct observation of the atomic structure of a sample. The defects can be clearly distinguished by analyzing the intensity profile in the HRTEM images.\textsuperscript{89–91} However, the HRTEM technique usually delivers lattice images rather than real atomic images. In contrast, the STEM technique has the ability to provide incoherent atomic images, whose intensity directly corresponds to the atomic number (Z-contrast). Namely, atoms can be distinguished by their brightness, making STEM technique more suitable for the comprehensive and systematic study of defective atomic structures in TMDs.\textsuperscript{92–95} Notably, since electron beam irradiation brings irreversible damage to TMDs, low voltage TEM imaging (∼80 kV) is commonly used in TMDs.

With the aid of STEM technique, intrinsic structural defects in TMDs can be classified into two categories according to their dimensionality: zero-dimensional (point) and one-dimensional (line) defects. Regardless of foreign atoms, there are two kinds of predominant point defects in TMDs: vacancies as a result of losing the M atom, X atom, MX\textsubscript{3}, or MX\textsubscript{2}o and antisite defects in which M (X) atoms substitute for vacancies (V\textsubscript{X}) and disulfur vacancies (V\textsubscript{S\textsubscript{2}}) (Figure 2a, left), and common antisite defects

Figure 1. Schematic illustration of four key aspects for the quality characterization of TMDs.
MoS2 (Figure 2a, right). Statistics based on STEM images depend on the specific synthesis method (Figure 2b-d). Sulfur vacancies are the predominant point defects in mechanical exfoliated and CVD-grown samples, while antisite defects represented by MoS and MoS2 are dominant in the samples deposited by physical vapor deposition (PVD). Therefore, the statistics of point defect density determined from STEM images are of great significance to the quality evaluation of TMDs. Single vacancies are mobile under electron irradiation and tend to agglomerate into line defects due to the low migration barrier. Interestingly, the band structure gradually shifts from semiconducting to metallic as these line defects increase in width.

As the most common line defect, a tilt GB is formed when two TMD grains with a lattice orientation mismatch are atomically stitched together with dislocation cores. These dislocation cores in GBs are composed of 5- and 7-fold (5/7) rings (Figure 2e, left), 4/6 fold rings, and 6/8 fold rings due to substitutions between metal and chalcogen atoms. GBs in MoS2 with atomic configurations of dislocation cores can be visually observed by STEM (Figure 2f). The Mo-oriented dislocation consists of 5/7-fold rings. One of five distinct Mo sites is energetically preferable for substitution by Sx forming the most stable structure (Figure 2g). In addition, mirror twin boundaries are observed by STEM when two domains with opposite lattice orientations (60° or 180°) in TMDs are spliced together (Figure 2h). They are composed of 4-fold rings, adopting a 4P type (Figure 2e right) and 4E type structures.

The HRTEM and STEM can provide accurate information on the defect structure with atomic-level spatial resolution, but both fail to characterize large-scale materials. Moreover, the sample must be transferred to a specific microgrid before being characterized.

In addition to the TEM techniques mentioned above, scanning tunneling microscopy (STM) can also be used to characterize the atomic structure of TMDs. Compared with TEM and STEM, STM is superior in characterizing point defects in MoS2 and Moiré fringes instead of line defects. At the same time, STM has the advantage of revealing the electronic properties influenced by point defects. However, STM is limited by the sample circumstances, failing for samples grown on insulating substrates.

Atomic force microscopy (AFM) is also a powerful method with high resolution at atomic level invented after STM. In contrast to STM, AFM provides a true three-dimensional view of the surface and does not require any special treatment of the sample. The defect structure in monolayer WS2 has been detected by the CO-tip noncontact AFM. Nevertheless, AFM is restricted to the scanning range and speed.

2.2. Defect Visualization by Etching or Adsorption. Compared with atomic characterizations tools, simple, effective, and fast methods for defect visualization of large-area TMDs are still lacking. In this view, conventional optical microscopy is an appealing technique to achieve macroscale characterization. However, it is challenging in recognizing ambiguous GBs due to its weak optical contrast. Based on the selective etching and controlled adsorption, the optical contrast of defects could be greatly increased, thus achieving defect visualization of TMDs in a large area.

Mild oxidation under moisture-rich ambient conditions is introduced to visualize GBs in WS2 domains by scanning electron microscope. However, the side effects of oxidation increase the number of defects in the whole crystalline domains, easily resulting in the PL intensity quenching effect. The key parameters in this experiment were heating temperature and humidity. Therefore, GBs in WS2 domains through controlled heating in air can be observed by an optical microscope. In addition, UV irradiation under moisture-rich air can generate oxygen and hydroxyl radicals, which can selectively functionalize GBs in WS2 to provoke morpho-
logical changes at the GBs. However, the PL spectral intensity at 756 nm decreases significantly after oxidation. The MoS₂ films on a SiO₂/Si substrate are exposed to vapor hydrofluoric acid (VHF) for 30–120 s, allowing GB visualization by optical microscopy. Nevertheless, this method is invasive for TMD films. Furthermore, a high-throughput method using mild hot H₂O enables visualization of all types of GBs unambiguously in TMD films under an optical microscope, which is nearly noninvasive to the TMD grain domains (Figure 3a).

Furthermore, discriminative adsorption behaviors among crystalline TMD films have been demonstrated to be a facile approach for detecting defects. The spin-coated liquid crystal (LC) molecules on the surface of the samples have a higher adsorption energy along the armchair direction, thus forcing them to align parallelly to this direction. Such alignment enables the visualization of GBs in CVD-grown MoSe₂ and WSe₂ films by the polarized microscopy (Figure 3b). As organic molecules cannot be desorbed clearly, this method greatly damages the quality of TMD films. Furthermore, GBs and point defects can be simultaneously visualized under dark-field optical microscopy, which is realized by anchoring silver nanoparticles on defect sites of MoS₂ under light illumination (Figure 3c). The point defect density can be estimated from the population of Ag particles, however, which also suffer from the destruction on the surface of TMD materials. The defects on 2D TMDs possess high reactivities due to the unsaturated chemical bonds, which enables spontaneous anchoring of metal atoms and clusters through redox or coordination.

Recently, a noninvasive method by one-pot adsorption of abundant sulfur particles on CVD-grown MoS₂ monolayers is developed to directly assess the crystal quality based on the preferential adsorption of domains with sulfur vacancies (Figure 3d). Importantly, the sample surfaces could be recovered after a mild annealing process.

Achieving simple, effective, and noninvasive defect visualization in large-scale TMDs by conventional optical microscopy is indispensible to assess the quality of TMDs. This will provide feedback to optimization of the growth conditions and facilitate the large-scale production and high-quality monitoring in the future device fabrication process. However, adsorption or etching will more or less bring damage to the film samples.

2.3. High-Throughput Characterization by Optical Spectroscopy. Noninvasive, high-throughput spectroscopic techniques, including Raman, SHG, and PL, provide an efficient route for the characterization of large-area TMDs without transfer process and no special requirements for substrates. All these techniques can be classified into two main categories: (1) the defects can be detected by the differences of the characteristic peak in Raman and PL; (2) the defects in TMDs can be easily monitored by nonlinear optical processes such as SHG, which is very sensitive to noncentrosymmetric materials.

2.3.1. Raman Spectroscopy. Raman spectroscopy is a universal method to determine vibration modes and provide a structural fingerprint of molecules. Therefore, Raman spectroscopy is widely used to characterize the unique properties of 2D layered materials, such as the number of layers, the effect of external electric perturbation or doping, and thermal conductivities. Basically, monolayer 2H-MX₂ has three Raman active modes associated with the A₁, E′, and E″ irreducible representations of the D₃h group. For the A₁ mode, the X atoms vibrate in the out-of-plane direction and the M atoms remain static. In addition, for the E′ and E″ modes, the movements of all atoms are in plane. However, for the E″ mode, the X atoms and M atoms move in opposite directions, while the E′ mode is related to the nonnull elements of the Raman tensor and does not appear in the commonly used Raman backscattering configuration. Therefore, the E′ and A₁ peaks are prominent Raman characteristic signals in the Raman spectra of monolayer TMDs. The typical phonon spectrum of MoS₂ is shown in Figure 4a. The defects in the lattice structure will alter the phonon modes,
leading to the change of the Raman peak position. Moreover, the oscillating strength of the phonons can also be affected by the defect density, which leads to the intensity changes of Raman peaks. Hence, Raman spectroscopy can be applied to monitor GBs in TMDs. For monolayer WSe2 exposed to UV light with a humidity level of ~65% for 6 min, darker positions in the Raman mapping image related to GB regions are visible (Figure 4b).115 Correspondingly, the intensity of the E2g peak is weaker than that of pristine materials, and the location of this peak also shifts slightly. Furthermore, the intensity of the A1g peak is also reduced (Figure 4c). In brief, this technique is a convenient and practical way to evaluate the effect of GBs in monolayer TMDs.

In addition, Raman spectroscopy can be used to detect point defects such as vacancies in TMDs. It has been reported that changes in the Raman modes vary with the number of S vacancies induced by electron beam irradiation in MoS2.131 In-depth experimental characterizations and theoretical calculations show that the shift of the E2g peak is clearly more remarkable than the shift of the A1g peak, indicating that the shift of the E2g peak is a better way to determine the S vacancy concentration. In addition, as shown in Figure 4e, the separation between these two peaks is an effective way to indicate the concentration of S vacancies. Furthermore, the appearance of new Raman peaks is a practical route to detect point defects of TMDs. The defect-induced new Raman scattering peaks arising in monolayer MoS2 flakes by Mn+ ion bombardment have also been investigated.128 As shown in Figure 4f, some new peaks appear when the density of defects increases. The most remarkable new peak is located at approximately 227 cm⁻¹, and the intensity is proportional to the density of defects.

2.3.2. Second Harmonic Generation. Nonlinear optical processes, especially SHG, are also a convenient way to detect defects in TMDs. SHG is the most fundamental process in nonlinear optics, which generates radiation at twice the frequency of the incident light. The SHG signal originates from different polarizations including electric dipoles, electric quadrupoles, and magnetic dipoles. These polarizations are dominated by the symmetry properties of crystalline materials.
Figure 5. PL spectroscopy in determining defects. (a) Band structure of monolayer TMDs near the band gap. (b) PL spectra of high-quality mechanically exfoliated TMDs at a temperature of 7 K. The PL spectra feature multiple peaks, including emission from the A exciton, trion and defect trapped exciton. Reproduced with permission from ref 142. Copyright 2020 The Author(s), under exclusive license to Springer Nature Limited. (c) PL spectra of CVD grown WS2 at a temperature of 7 K. The decrease in quality brings a broadened emission peak. Reproduced with permission from ref 143. Copyright 2020 The Royal Society of Chemistry. (d) Valley polarization of WSe2 monolayer. Reproduced with permission from ref 148. Copyright 2017 American Physical Society. (e) PL characterization of a CVD grown MoS2 sample. Reproduced with permission from ref 91. Copyright 2013 Nature Publishing Group.

The TMD monolayers have relatively large nonlinear susceptibility and noninversion symmetry. Therefore, the SHG signal has the capacity to acquire abundant information about the structural properties, especially the GBs and domain edges of TMDs.132–139

A schematic diagram of the SHG experimental setup is shown in Figure 4g.140 The MX2 monolayer is excited by the input beam with frequency ω and generates an output beam with a frequency of 2ω. Monolayer MX2 belongs to the D₃h point group with in-plane 3-fold rotation symmetry. The parallel and perpendicular components of the SHG signal are represented as Iₚ = I cos²(3θ) and Iᵥ = I sin²(3θ), respectively, where θ is the angle between the polarization direction and crystalline armchair direction. The maximum value of Iₚ appears when the polarization of the excitation laser is parallel to the crystalline armchair direction (Figure 4h). Therefore, SHG exhibits considerable potential in GB visualization because of its sensitivity to symmetry variations. Figure 4i shows an SHG image of monolayer MoS2 grown by the CVD method. The SHG intensity is reduced along the GBs as a result of destructive interference of waves from neighboring grains, thus, the GBs in SHG mapping are clearly visible.

2.3.3. Photoluminescence Spectroscopy. Monolayer TMDs can emit strong PL due to their direct bandgap nature and excitonic effects.143 The typical band structure of TMDs is sketched in Figure 5a. After monolayer TMDs are excited by a high-energy photon, carriers will rapidly relax to the substable excited state with the lowest energy, i.e., in an exciton state. An exciton is formed by an electron in the conduction band minimum and a hole in the valence band maximum located at the same valley with the opposite spin via attractive Coulomb interaction. Owing to the distinct states induced by various defects such as chalcogen vacancies, bound excitons induced by defects can also exist with lower energy. As for the electronic states, the emergence of defects brings defect states between the conduction and valence bands and gives rise to the peak position deviation of PL. Besides, the increased nonradiative recombination rate caused by the defect states also leads to the PL intensity attenuation.

Typical PL spectra of high-quality mechanically exfoliated TMDs are shown in Figure 5b, where BN-encapsulation is used to reduce the impact on PL spectra from the substrate, and the experiment is performed at cryogenic temperatures below 20 K to reduce the broadening of spectra caused by phonons.142 The exciton peak labeled with "*" can be clearly separated from the defect state luminescence for every TMD material. By inserting a graphene layer, the defect peak can be filtered out. However, it is not possible to encapsulate every sample with BN, and the quality of the TMDs prepared in other ways is hard to compare with that of mechanically exfoliated TMDs.

For the CVD-grown TMD monolayer, the PL spectra will broaden (Figure 5c). It is expected that the intensity of the separate peaks can be used to evaluate the quality of the sample. A cryogenic PL spectrum is observed in CVD-grown MoS2, which can be analyzed via multiple peak fitting. The whole spectrum can be divided into five peaks.143 The bound exciton peaks X⁰₂ and X⁰₁ reflect the density of S vacancy defects.144 The charged exciton peak X⁻ originates from the doping of the sample, where a negative charged exciton means a three-particle state consisting of two electrons and one hole.145

The exciton peak A in the PL spectra is described above and shown in Figure 5b. The exciton peak B represents an exciton formed by an electron and a hole with spin opposite to those in the A exciton. Peak B has lower intensity than peak A and appears at a higher energy. After attaining the cryogenic PL spectrum of the sample, the intensity of the bound exciton
peaks can be used to evaluate the density of S vacancies, which can be passivated easily by oxygen in air. The relative intensity of the A/B exciton peak ratio is also a useful index for defect density, because the lifetime of nonradiative recombination is shorter than that of radiative recombination for the A exciton and thus will significantly affect the intensity of the A exciton peak while only slightly affecting the B exciton peak because the latter has the shortest lifetime.146

Simultaneously, valley polarization is one of the most famous unique optical properties of TMDs in 2H phase. As shown in Figure 5a, TMDs have two valleys with opposite optical circular polarization selectivity. If we excite the material with fully polarized photons, in most luminescence cases, the excitons will recombine in the same excitation valley. However, Coulomb interaction and some defect states, which can introduce intervalley scattering of excitons, make the PL spectrum not fully polarized.147 A typical valley polarization spectrum of monolayer WSe2 is shown in Figure 5d.148 If defects affect the nonradiative recombination channel more than the intervalley scattering process, valley polarization degree will increase. However, some defect states can introduce intervalley scattering of excitons, and thus the degree of circular polarization may contrarily decrease.149,150 The valley polarization somewhat reflects the quality of the sample.

In addition to point defects such as the chalcogen vacancy mentioned above, GBs can be recognized by PL spectrum mapping.91 As shown in Figure 5e, the islands at the GBs show strong PL modifications including quantum yield, peak position, and PL peak width, which demonstrate that PL is strongly affected by the presence of GBs.

However, optical spectroscopy indeed has its own disadvantages. The spatial resolution of far field optical spectroscopy is limited by the laser spot size of ~500 nm. Besides, optical spectroscopy can also be influenced by other factors including strain, electron doping and substrate. In a word, Raman, SHG and PL are all fast and contactless techniques to uncover the quality-property relationships of 2D TMDs materials through characteristic peak or mapping. Among them, Raman spectra is the most sensitive technique to characterize point defects or GBs in the most TMDs that have Raman-active modes. PL spectra is widely used for characterizing defects in semiconducting materials through variations of the characteristic peak intensity and width. However, this method will be invalid for metallic materials and semiconductor with no luminescence. SHG is very powerful for identifying the crystal orientation, while this method can only be applied to central symmetry broken materials.

### 2.4. Electrical Transport Measurement by FETs.

Excellent electrical properties are a prerequisite for TMDs applied to electronic and optoelectronic devices in which the FETs are the most fundamental elements.151–156 Thus, to characterize the electronic quality, TMDs-based FETs should be fabricated and tested accurately and scientifically. For a typical FET, the most important parameters are carrier mobility (μ), subthreshold swing (SS), and the on/off ratio (I_on/I_off). These three values are usually used to evaluate the electrical properties of the same TMD obtained by different methods. Generally, these three parameters are close to the theoretical value, which means that the TMD has relatively high quality. Therefore, greater carrier mobility, lower subthreshold swing, and higher on–off ratio mean better quality of measured samples of TMD, which result from less carriers scattering during transport in the crystal with fewer defects.

Although the electrical properties and electronic structure of TMDs have been studied since 1960s,157 the application of related devices has been consistently limited. WSe2 crystal was first applied to FETs until 2004.158 The charge carrier mobility is up to 500 cm² V⁻¹ s⁻¹ for the p-type conductivity in the WSe₂-based FETs at room temperature, comparable to that in the best single-crystal Si-based FETs. The first micromechanical exfoliated single-layer MoS₂-based FETs were fabricated in 2011.159 The mobility of single-layer MoS₂ FETs with a hafnium oxide gate dielectric is at least 200 cm² V⁻¹ s⁻¹.

In principle, the device performance of atomically thin TMD-based FETs depends on a variety of factors, such as the material quality, thickness, substrate, contacts, environment. Here we focus primarily on the effects of the material quality on the electrical transport characteristics. The electrical performances of monolayer TMD-based FETs at room temperature are summarized in Table 1. It is obvious that single crystal TMDs show excellent electrical properties. However, the mechanically exfoliated single crystal TMD devices are limited at a small scale, making them unfavorable for industrial applications.

<table>
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<th>method</th>
<th>TMDs</th>
<th>orientation</th>
<th>on/off ratio</th>
<th>field-effect mobility (cm²-V⁻²-s⁻¹)</th>
<th>SS (mV/dec)</th>
<th>ref</th>
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<td>MoS₂</td>
<td>single crystal</td>
<td>&gt;10⁶</td>
<td>44</td>
<td>410</td>
<td>170</td>
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<tr>
<td>exfoliated</td>
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<td>&gt;10⁶</td>
<td>250</td>
<td>60</td>
<td>38</td>
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<tr>
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<td>83</td>
<td>-</td>
<td>171</td>
</tr>
<tr>
<td>exfoliated</td>
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<td>&gt;10⁶</td>
<td>50</td>
<td>-</td>
<td>172</td>
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<tr>
<td>MOCVD</td>
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<td>10⁷</td>
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<tr>
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<td>102.6</td>
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With the development of growth methods, especially CVD, wafer-scale TMD monolayers provide a promising way to further implement realistic systems. For the first time, batch-fabricated MoS₂ FET devices on 4-in. MoS₂ films have been achieved and demonstrated the electrical uniformity of wafer-scale monolayer MoS₂ films grown by the metal–organic CVD (MOCVD) method.152 All the devices show similar field-effect mobilities near 30 cm² V⁻¹ s⁻¹ and a high on/off conductance ratio of approximately10⁶. This makes it possible to realize atomically thin integrated circuitry. However, the tilt GBs in TMDs films reduce the electrical transport properties,92,160 resulting from the changes of electronic structure around the GBs.93,161

Typical fabricated FET devices based on large-area MoS₂ show higher electrical quality at room temperature when MoS₂ fabricated in 2011.37 The mobility of single-layer MoS₂ FETs with a hafnium oxide gate dielectric is at least 200 cm² V⁻¹ s⁻¹.

To achieve field-effect mobility of 500 cm² V⁻¹ s⁻¹, the charge carrier density needs to be about 10³⁹ cm⁻³. This can be achieved by controlling the density of monolayer TMDs, or by using other methods to enhance the electrical quality of TMDs. In principle, these three parameters are close to the theoretical value, which means that the TMD has relatively high quality. Therefore, greater carrier mobility, lower subthreshold swing, and higher on–off ratio mean better quality of measured samples of TMD, which result from less carriers scattering during transport in the crystal with fewer defects.

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has single-crystalline orientations. Highly oriented 4-in. monolayer MoS₂ FET devices have an average mobility of approximately 70 cm² V⁻¹ s⁻¹ and an on/off ratio of 10⁴ after transferred onto SiO₂. A 2-in. wafer-scale single-crystal MoS₂ grown on sapphire also shows higher performance in FETs. The carrier mobility (102.6 cm² V⁻¹ s⁻¹) and saturation current (450 μA μm⁻²) are the highest records among wafer-scale monolayer MoS₂ films by now. The FETs also show excellent uniformity in carrier mobility and subthreshold swing, with variations of 15 and 11%, respectively. The devices with a 500 nm channel length exhibited an SS of 210 mV dec⁻¹ and the I_on/I_off is nearly 10⁴. The statistical analysis of the mobility and SS also exhibits Gaussian distributions.

Moreover, it is a common strategy to improve the electronic properties of 2D semiconductors by repairing atomic defects and restoring the intrinsic lattice structure. A facile low-temperature thiol chemistry route is used to repair the sulfur properties of 2D semiconductors by repairing atomic defects. The statistical analysis of the mobility and SS also exhibits Gaussian distributions.

In brief, 2D TMDs with abundant electronic band structure hold great promise for future electronic and optoelectronic devices. These applications are strongly dependent on the electrical properties of 2D materials-based FETs. High performance of these FETs means the quality of used materials is high. However, the assessment of ultrathin 2D layered materials-based-FET performance remains challenges since some factors such as contact resistance, Schottky barrier, and metal doping will also bring unreliable results.

3. SUMMARY AND OUTLOOK

In this Review, we have highlighted four commonly used characterization techniques for monitoring the material quality of TMDs from nanoscale atomic structures to large-area visualization. In summary, each method has its advantages and drawbacks. TEM, STEM and AFM can provide accurate information of the defect structure with atomic-level spatial resolution, while they are time-consuming for a large-scale characterization. Selective etching and adsorption take the advantage of facile and large-scale fast imaging of defects, while they will more or less bring damage to the sample. Spectroscopic-based methods are fast, contactless, and non-destructive techniques, while they are limited by the spatial resolution and cannot directly give a correspondence between spectrum and defect types. FET can directly tell us the material quality from the view of devices, while the device parameters can also be significantly affected by the fabrication process. Therefore, the combination of different methods will be very comprehensive for the monitoring of material quality. Nonetheless, there is still a significant need to develop advanced techniques for defect engineering. For example, in situ evaluation of defects during CVD grown or device operation for TMDs are highly needed but still currently lacking. Additionally, once the vacancy introduced during sample synthesis has been detected through characterization, how to repair them is the next question to be solved. Finally, a unified standard for a quality evaluation is waiting to be established for further industrialization.

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## ACKNOWLEDGMENTS

This work was supported by the Key R&D Program of Guangdong Province (2019B010931001, 2020B010189001, and 2018B030327001), the National Natural Science Foundation of China (92163206, 52025023, 51991342, 52021006, 51991344, 52100115, and 11888101), the China Postdoctoral Science Foundation (2021T140022), the Strategic Priority Research Program of the Chinese Academy of Sciences (XDB33000000), the Beijing Natural Science Foundation (JQ19004), and the Pearl River Talent Recruitment Program of Guangdong Province (2019ZT08C321).

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